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Confirmation Letter

To,
P Gopala Krishnaiah
Published in : Volume 8 | Issue 6 | 2021-06-30



Subject: Publication of paper at International Journal of Emerging Technologies and Innovative Research .

Dear Author,

With Greetings we are informing you that your paper has been successfully published in the International Journal of Emerging Technologies and Innovative Research (ISSN: 2349-5162). Following are the details regarding the published paper.

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UGC Approval : UGC and ISSN Approved - UGC Approved Journal No: 63975 | Link: <https://www.ugc.ac.in/journallist/subjectwisejournallist.aspx?tid=MjM0OTUxNjI=&&did=U2VhcmNoIGJ5IEITU04=>

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Title of Paper : Optimization of Process Parameters for Material Removal Rate Kerf Width and Surface Roughness in Wire Cut Electrical Discharge Machining Process

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Thank you very much for publishing your article in JETIR. We would appreciate if you continue your support and keep sharing your knowledge by writing for our journal JETIR.

Editor In Chief

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